IEEE SW Test Workshop Semiconductor Wafer Test Workshop

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Automatic Probe Assembly Machine



Technology & Science Enabler

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1st Section. Conventional Methods of Assembly <u>CPC (Compact Probe Card)</u>

• High Pin Courter to 23,000 Pins (depend on ATE resource)

Large Touch Down
Applie Temperature
(-30 ~ 75umX75um)
Stable along with Thermal Deformation
1T/D 12" NAND Flash CPC



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1st Section. Conventional Methods of Assembly

<u>CPC Structure (Sectional View)</u>



1st Section. Conventional Methods of Assembly <u>Conventional Manufacturing Process</u>.

1.Probe Bending



2.Positioning



3. Aligning



Disadvantages

1. Labor & Time Required

2. Less Reliable for Partial Inspection

3. Technicians Demanded



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^{2nd Section. Innovative Methods of Assembly <u>Automatic Probe Assembly Machine (IM-800)</u>}



1. Objectives

- Full Probe Inspection
- Productivity Improvement
- Quality Consistency
- 2. Features
- High Resolution Image Processing
- Highly Accurate & Repeatable Positioning

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2nd Section. Innovative Methods of Assembly

IM-800 Process Steps



- 1. Loading a Pin from Cassette
- 2. Probe Inspection before Bending
- 3. Bending
- 4. Probe Inspection after Bending
- 5. Probe Tilt Inspection
- 6. Probe Positioning



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1. Full Inspection & Data Logging

- Inspect Tip Length, Bending Angle, Probe Tilt
- Record Inspection Data

2. High Precision Repeatability

- Increased the Uniformity of Tip Length
- Increased the Uniformity of Probe Bending Angle



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2nd Section. Innovative Methods of Assembly

Full Inspection





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2nd Section. Innovative Methods of Assembly High resolution Image processing

Probe Bending Angle / Tip Length / Tilt Check



Specifications		
FOV (Field of View)	1.6mm * 1.2mm	
Accuracy	± 2µm	
Repeatability	± 2µm	



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2nd Section. Innovative Methods of Assembly <u>Repeatability</u>





♦ Probe Bending Angle Tolerance



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2nd Section. Innovative Methods of Assembly

<u>Repeatability</u>

Comparative data of Tip Length Tolerance



2nd Section. Innovative Methods of Assembly <u>Repeatability</u>

◆ Comparative data of Probe Bending Angle Tolerance



2nd Section. Innovative Methods of Assembly <u>Effects</u>

1. Productivity

- Enhanced Throughput
- Reduced Products Delivery

2. Quality

- Increased the Accuracy of the Tip Dia. By Precise Bending Angle of the Probe

- Enhanced Scrub Marks by Full Probe Inspection



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2nd Section. Innovative Methods of Assembly <u>Productivity Effects</u>

1. Shorten Delivery Time by Automatic Process

VS

- CPCTM New Product : $5 \rightarrow 4$ weeks
- CPCTM Repeat Order : $4 \rightarrow 3$ weeks









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2nd Section. Innovative Methods of Assembly **Productivity Effects**





Time for 1pin	15 sec	30sec
Working time	29 hours	* 83%
Total Pins in a day	4800	960
Comparison	5X	X



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2nd Section. Innovative Methods of Assembly <u>Productivity Effects</u>





5 Technicians



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2nd Section. Innovative Methods of Assembly Quality Effects

• Measuring Equipments





1. WaferWoRx

2. ProbeWoRx



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2nd Section. Innovative Methods

Quality Effects

• Reducing Tip Length Gap by Probe Insert Depth Uniformity



2nd Section. Innovative Methods

Quality Effects

• Reducing Tip Dia. Dispersion by Probe Insert Depth Uniformity





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2nd Innovative Methods of Assembly Quality Effects

• Enhanced Scrub Marks by Full Probe Inspection

a) Before



<u>Max. Size</u> X: 29.0μm

Y: 13.6µm





<u>Max. Size</u> X:22.2μm Y:12.0μm



<u>Min. Size</u> X : 18.8μm Y : <u>12.7μm</u>

 $X : 10.2 \mu m$

Υ: 0.9μm

<u>GAP</u>



<u>Min. Size</u> X : 17.9μm Y : 11.3μm <u>GAP</u> X : 4.3μm

Υ: **0.7**μm



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3rd Section. Conclusion Summary

- Got Rid of the Manual Drawbacks by Automation
- Improved the Reliability & Accuracy by Q.C & Q.A
 - Automatic Full Inspection
 - Reduce Tolerance of Tip Length and Bending Angle
 - Enhance Scrub Marks Quality
- Shorten the Delivery
 - One Week Faster



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3rd Section. Conclusion Future Action Items

• Reduce TAT (Total Acting Time)

- 15sec \rightarrow 12sec
- Enhance the Uniformity
 - Tip Length & Probe Bending Angle
 - Tip Diameter & Scrub Mark

• Increase Automation



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Thank You for Kind Attention!

Question?

